INFORMATION DISCLOSURE CITATION

Docket Number (Optional)	Application Number				
LEE.002	NEW				
Applicant(s) Shone FUJA					
Filing Date	Group Art Unit				

		(Use several sheets if neces	sary)		Shone FUJA				
·					Filing Date January 5, 200		Group Art Unit To Be Assigned		
				U.S. PAT	ENT DOCUMENTS				
'EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE		NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
D\-	A	5,739,567	04/14/1998	WONG	,				- MAIL
	В	5,770,514	06/23/1998	MATSU	ЉА et al.	<u> </u>			
	С	6,544,824	04/08/2003	PRADE	CEP et al.				
DV	D	6,365,452	04/02/2002	PERNG	et al.				
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			····	FOREIG	N PATENT DOCUMENTS	 	_		
	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation YES NO		
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	<u> </u>								· .
		ID Monetake et al. 1	A CV F-L-14-1				ate, Pertinent Pa	-	
Þ∨		R. Muralidhar et al., "A 6V Embedded 90nm Silicon Nanocrystal Nonvolatile Memory", DigitalDNA Laboratories and the embedded Memory Center, 2003 IEEE, 4 pgs.							
DV		B. De Salvo et al.,"Ho	w far will Silicon r	anocrysta	ls push the scaling limits of	NVMs techt	ologies?", 2003	i IEEE, 4 p	ogs.
EXAMINE	R <i>(</i>	101		·	DATE CONSIDERED	-1 -1 -		<u></u>	

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

67/06/05